
Computationally efficient modelling of pattern dependencies in the micro-embossing of thermoplastic polymers

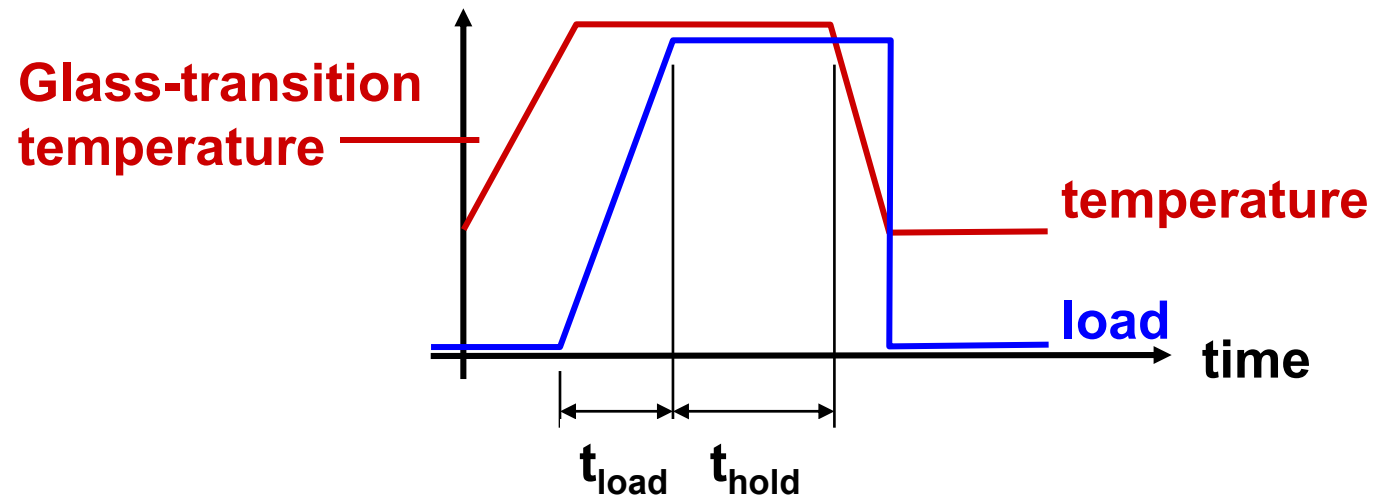
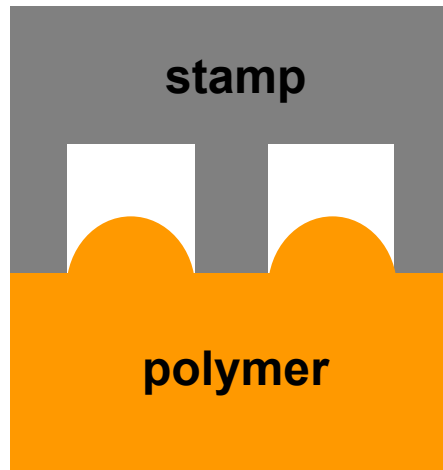
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24 September 2007

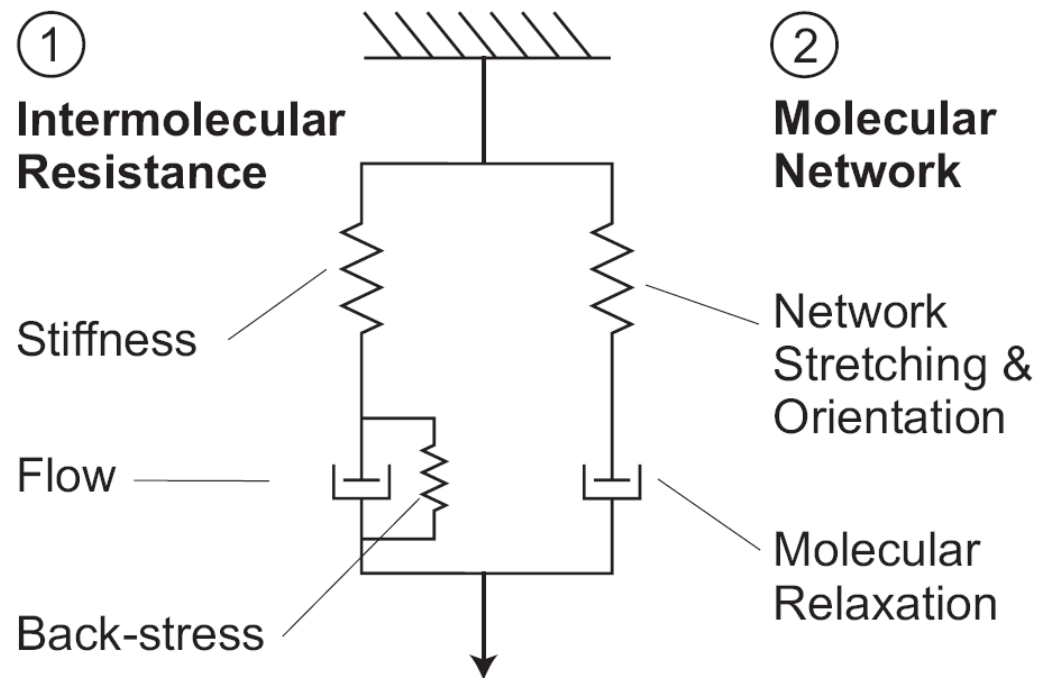


Hot micro- and nano-embossing

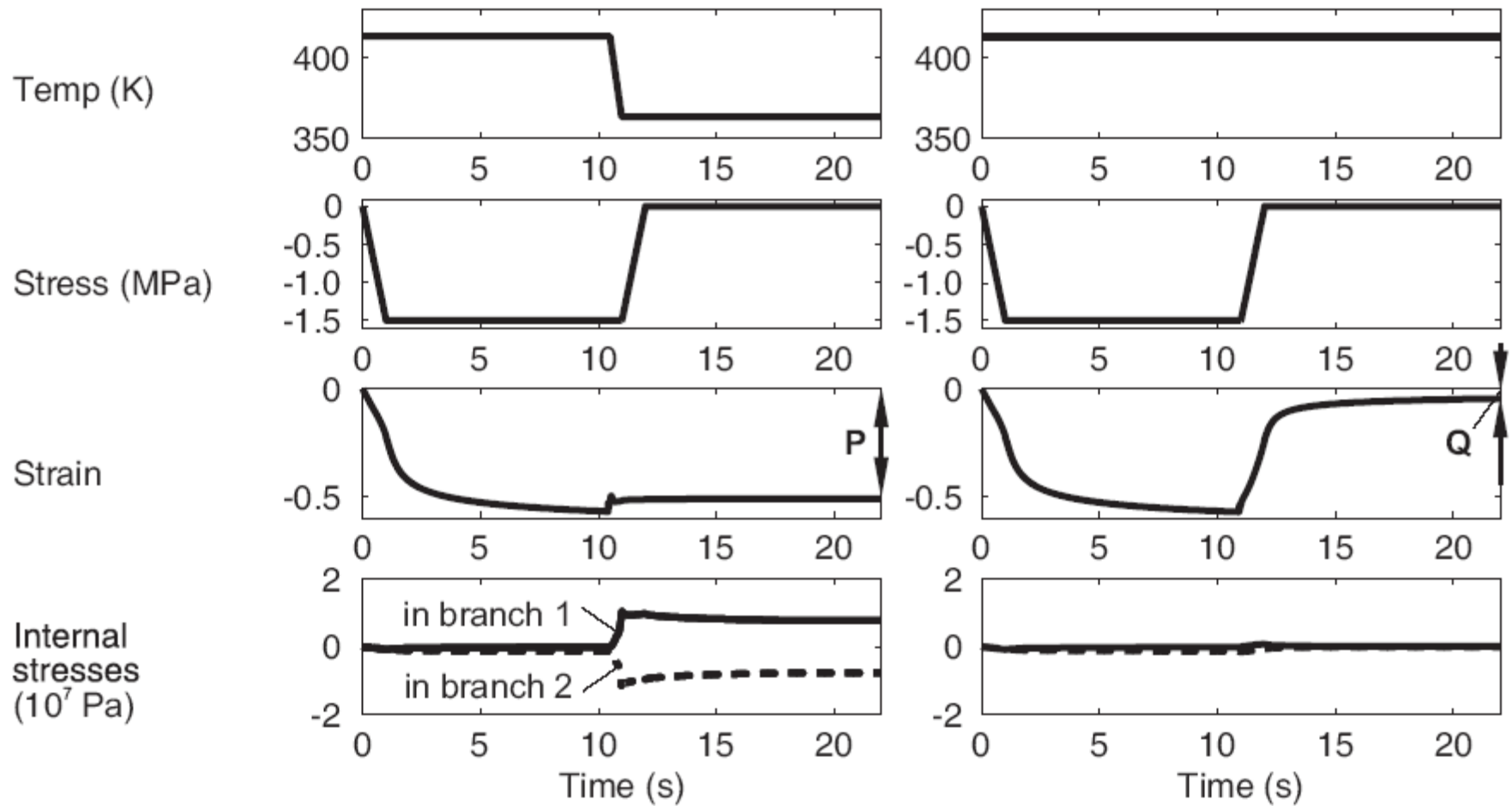


- To choose an optimal process, we need to assign values to
 - Heat
 - Time
- Our load and temperature are constrained by
 - Equipment
 - Stamp and substrate properties

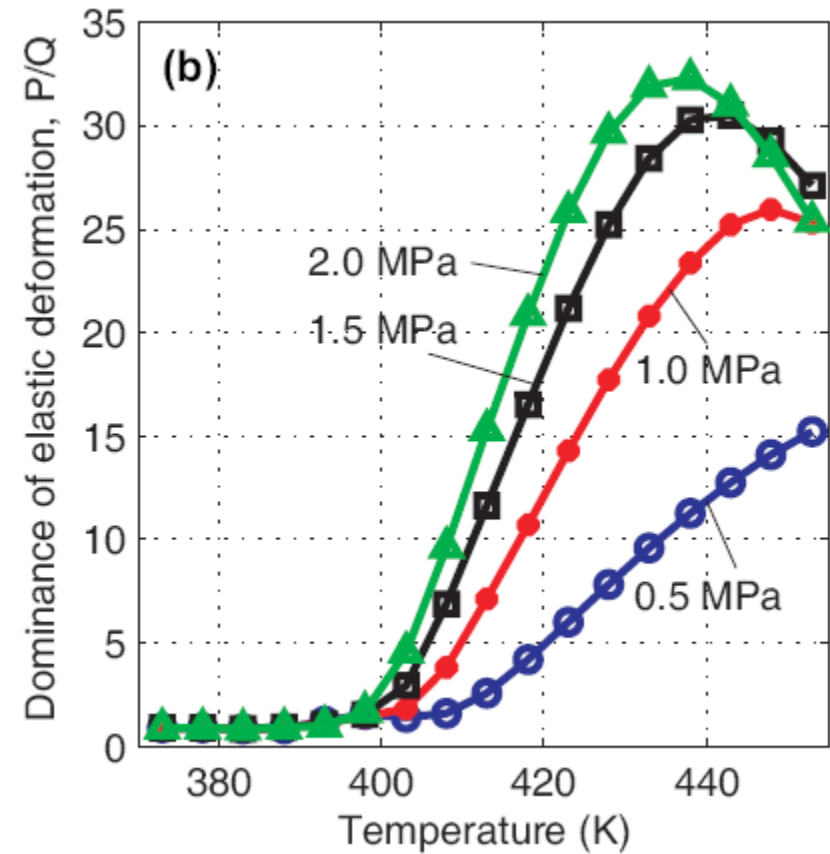
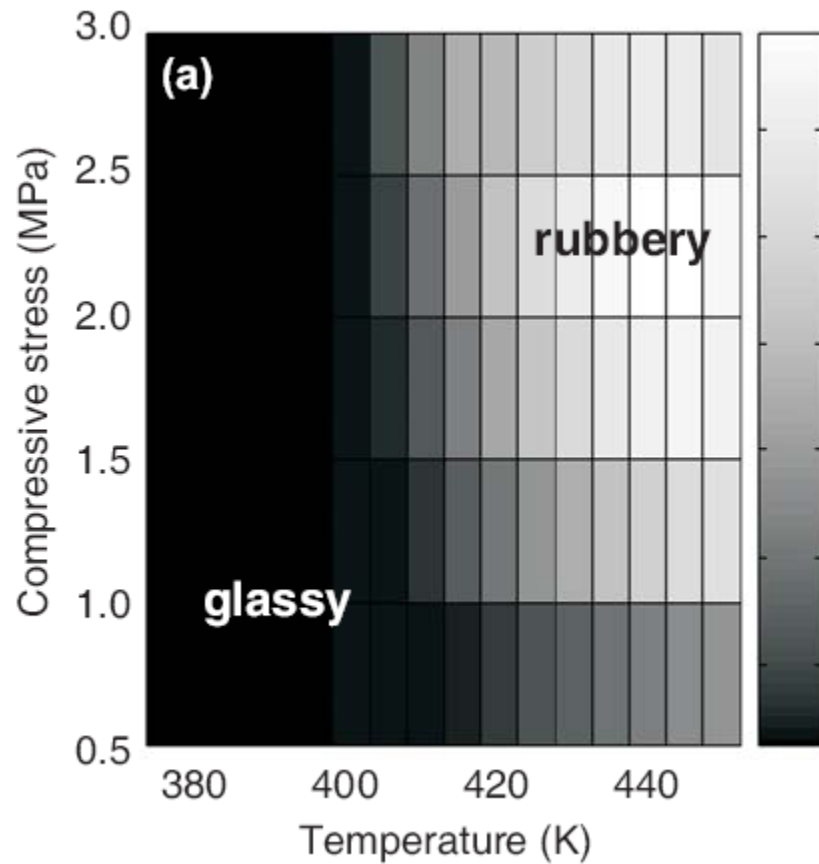
PMMA in compression



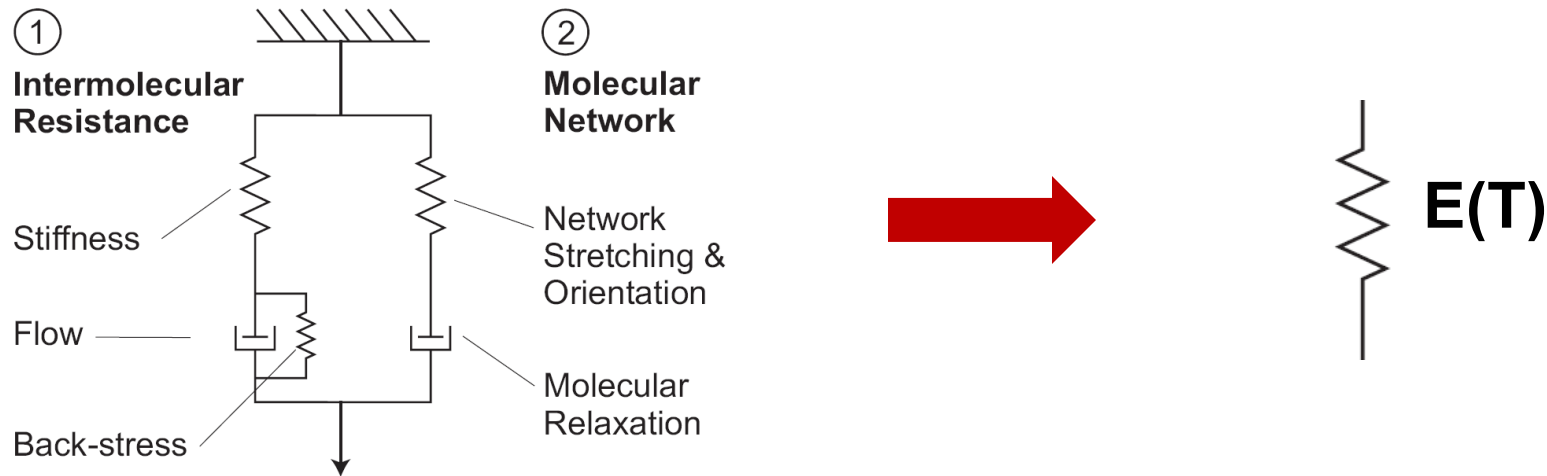
PMMA in compression, 140 °C



PMMA in compression ($T_g = 105\text{ }^\circ\text{C}$)



Starting point: linear elastic material model

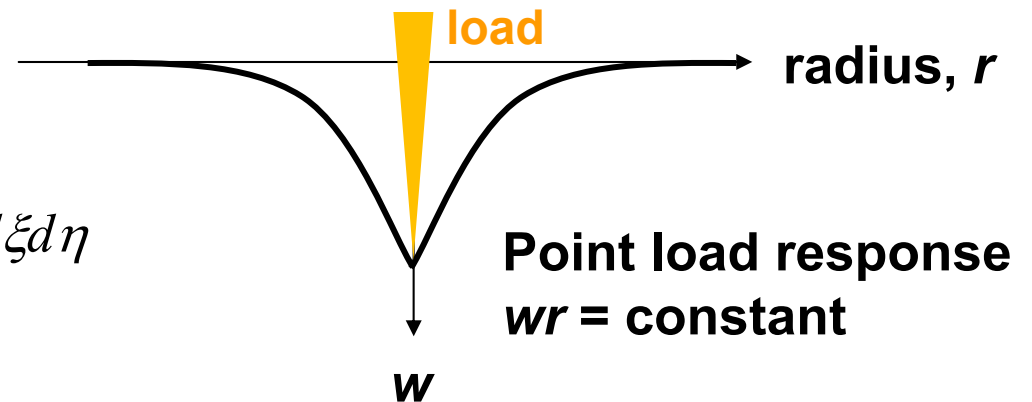


- **Embossing done at high temperature, with low elastic modulus**
- **Deformation 'frozen' in place by cooling before unloading**
- **Wish to compute deformation of a layer when embossed with an arbitrarily patterned stamp**
- **Take discretized representations of stamp and substrate**

Response of material to unit pressure at one location

General load response:

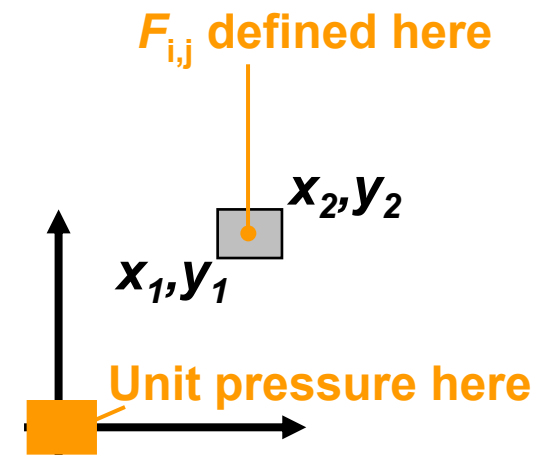
$$w(x, y) = \frac{1-\nu^2}{\pi E} \iint \frac{p(\xi, \eta)}{\sqrt{(x-\xi)^2 + (y-\eta)^2}} d\xi d\eta$$



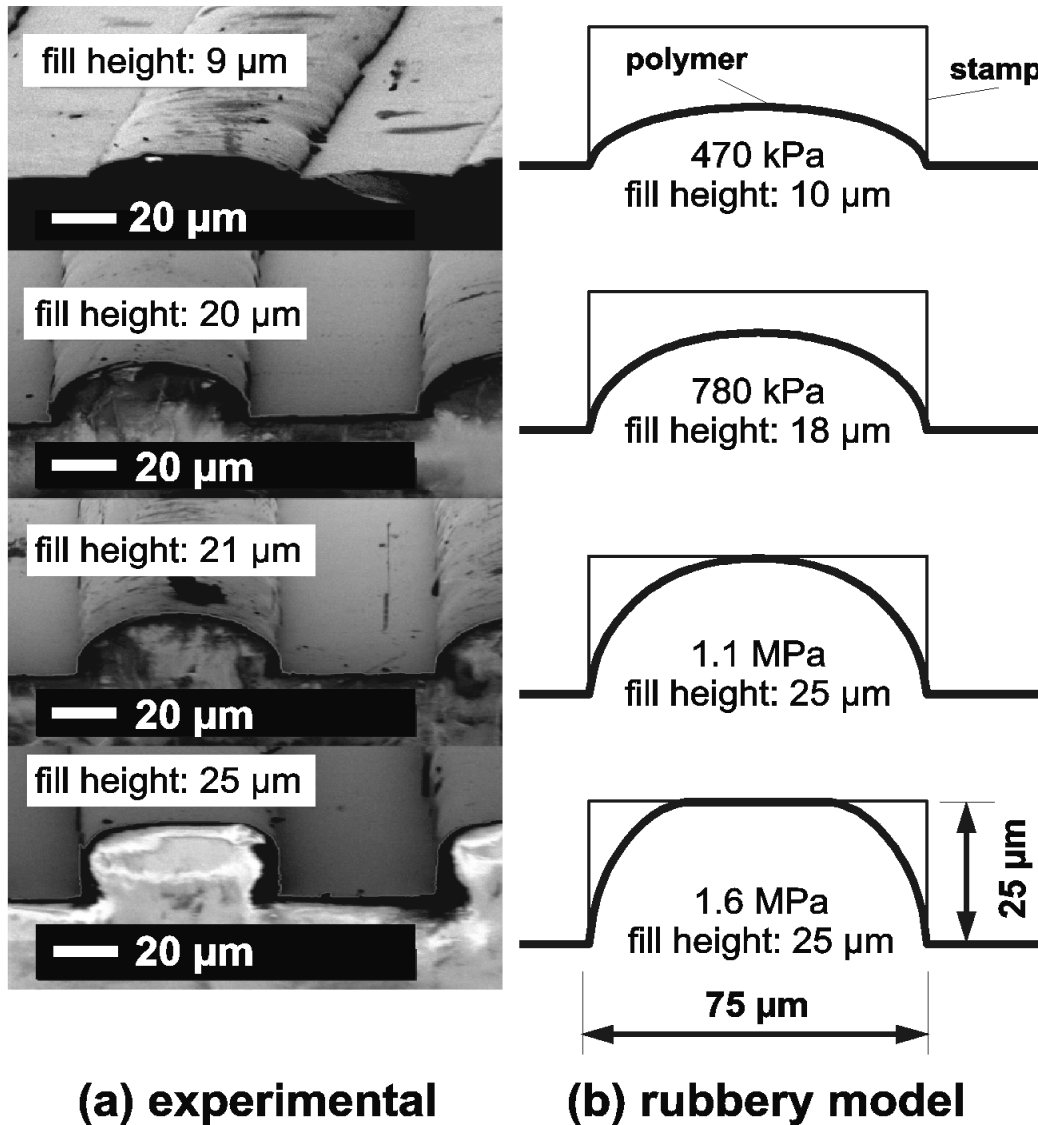
Response to unit pressure in a single element of the mesh:

$$F_{i,j} = \frac{1-\nu^2}{\pi E} [f(x_2, y_2) - f(x_1, y_2) - f(x_2, y_1) + f(x_1, y_1)]$$

$$f(x, y) = y \ln(x + \sqrt{x^2 + y^2}) + x \ln(y + \sqrt{x^2 + y^2})$$



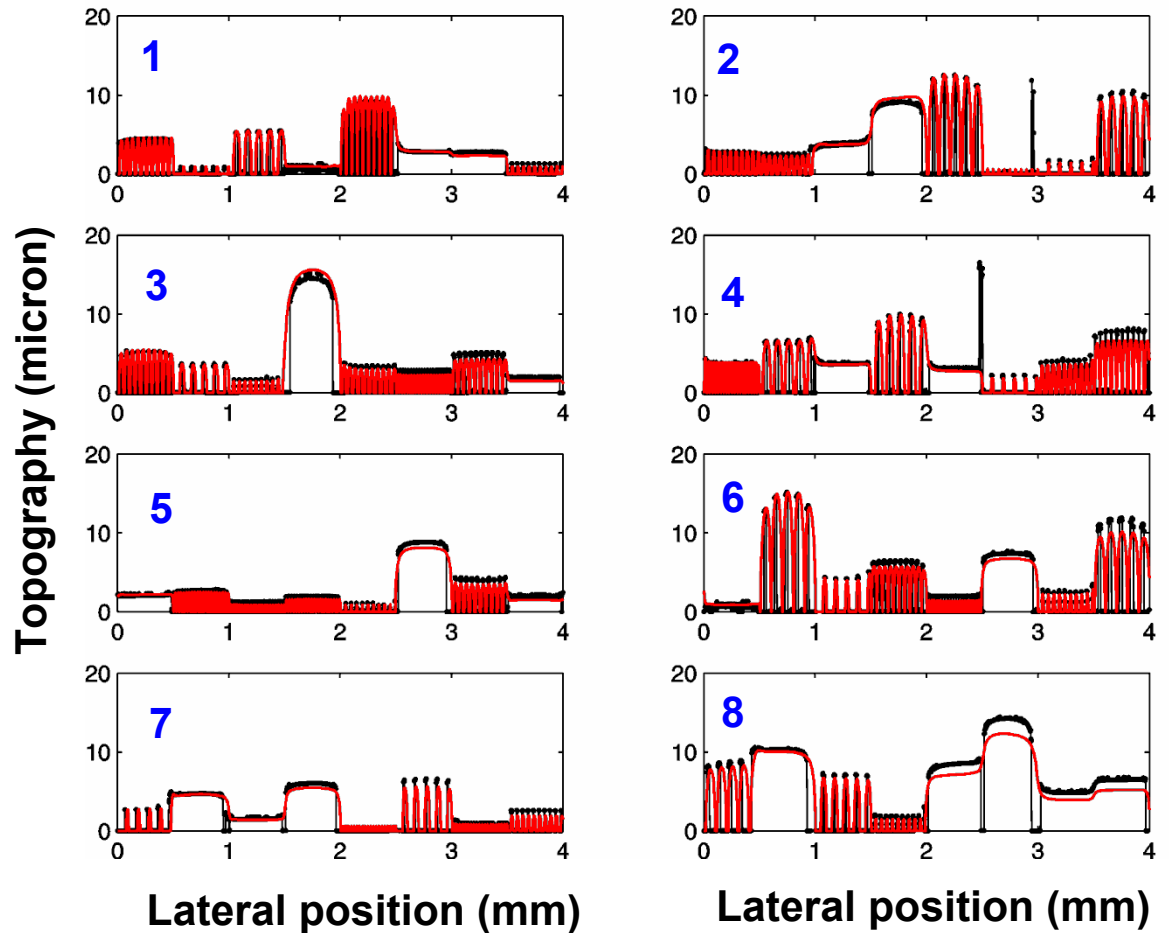
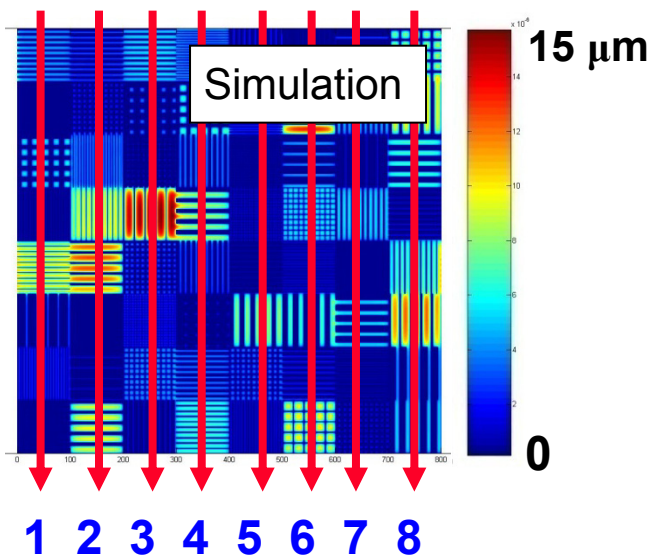
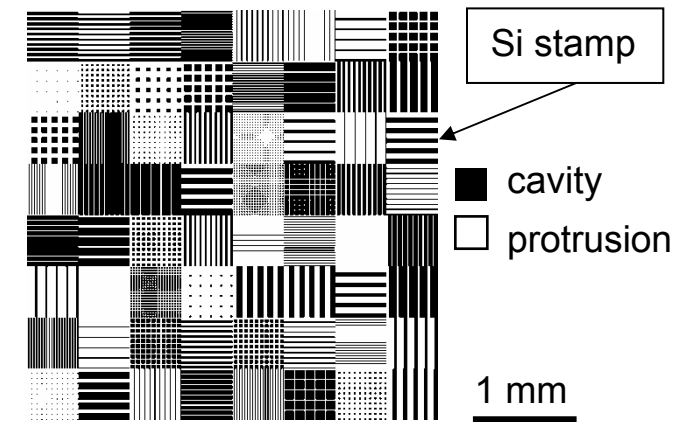
1-D verification of approach for PMMA at 130 °C



- Iteratively find distribution of pressure consistent with stamp remaining rigid while polymer deforms
- Fit elastic modulus that is consistent with observed deformations

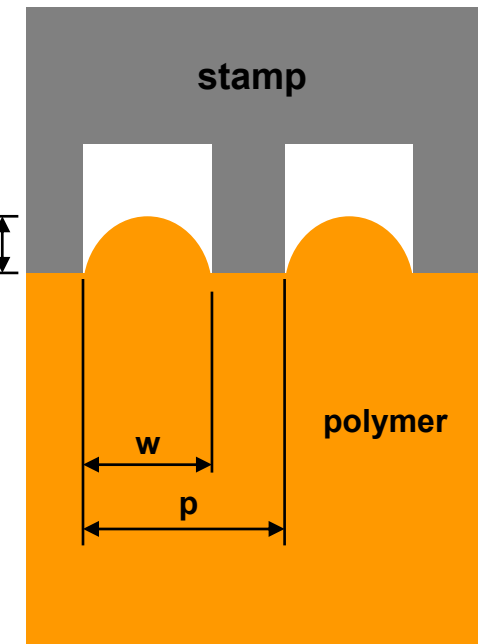
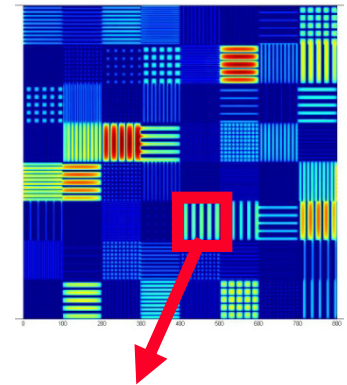
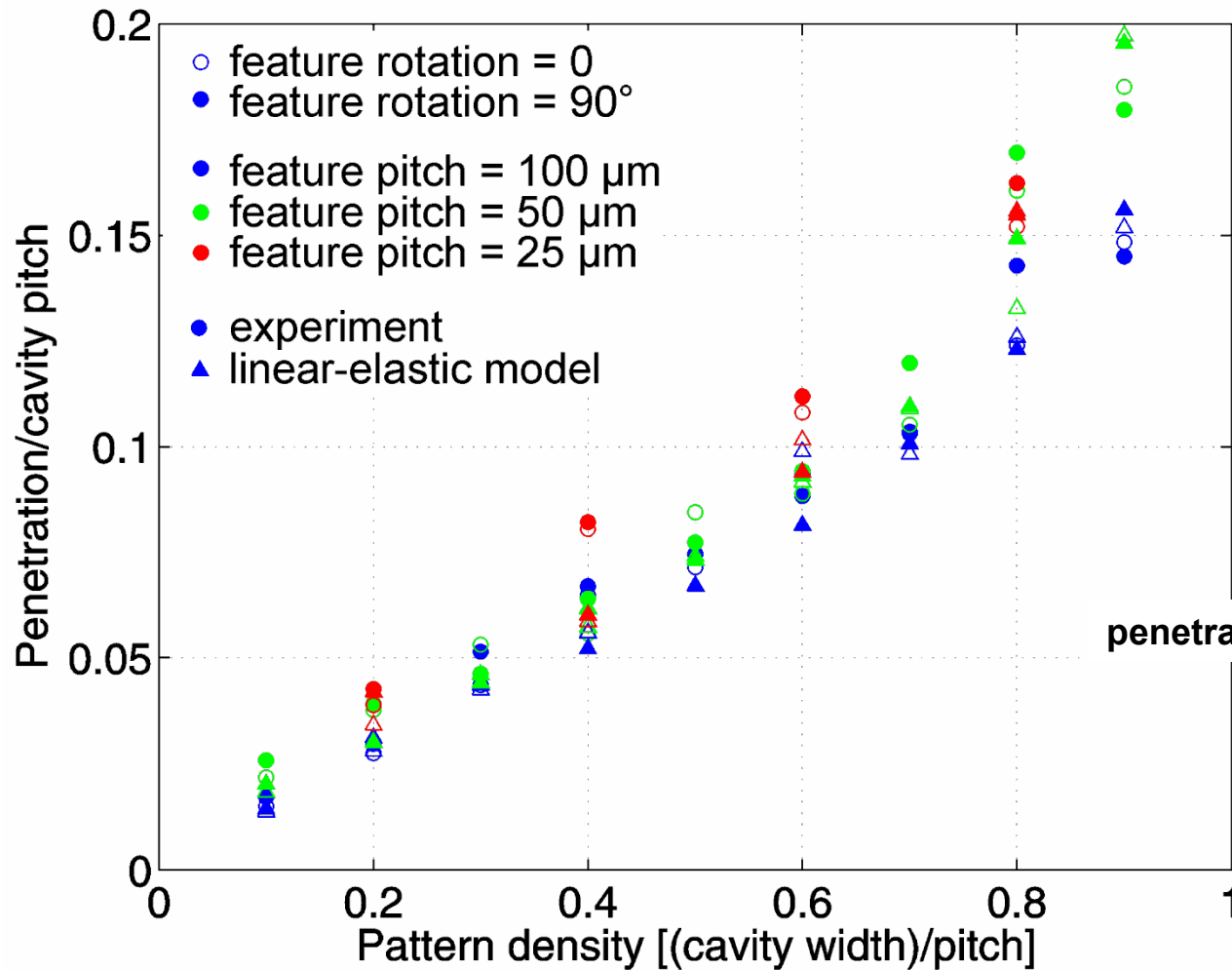
Extracted Young's modulus ~ 5 MPa at 130 °C

2-D linear elastic model succeeds with PMMA at 125 °C

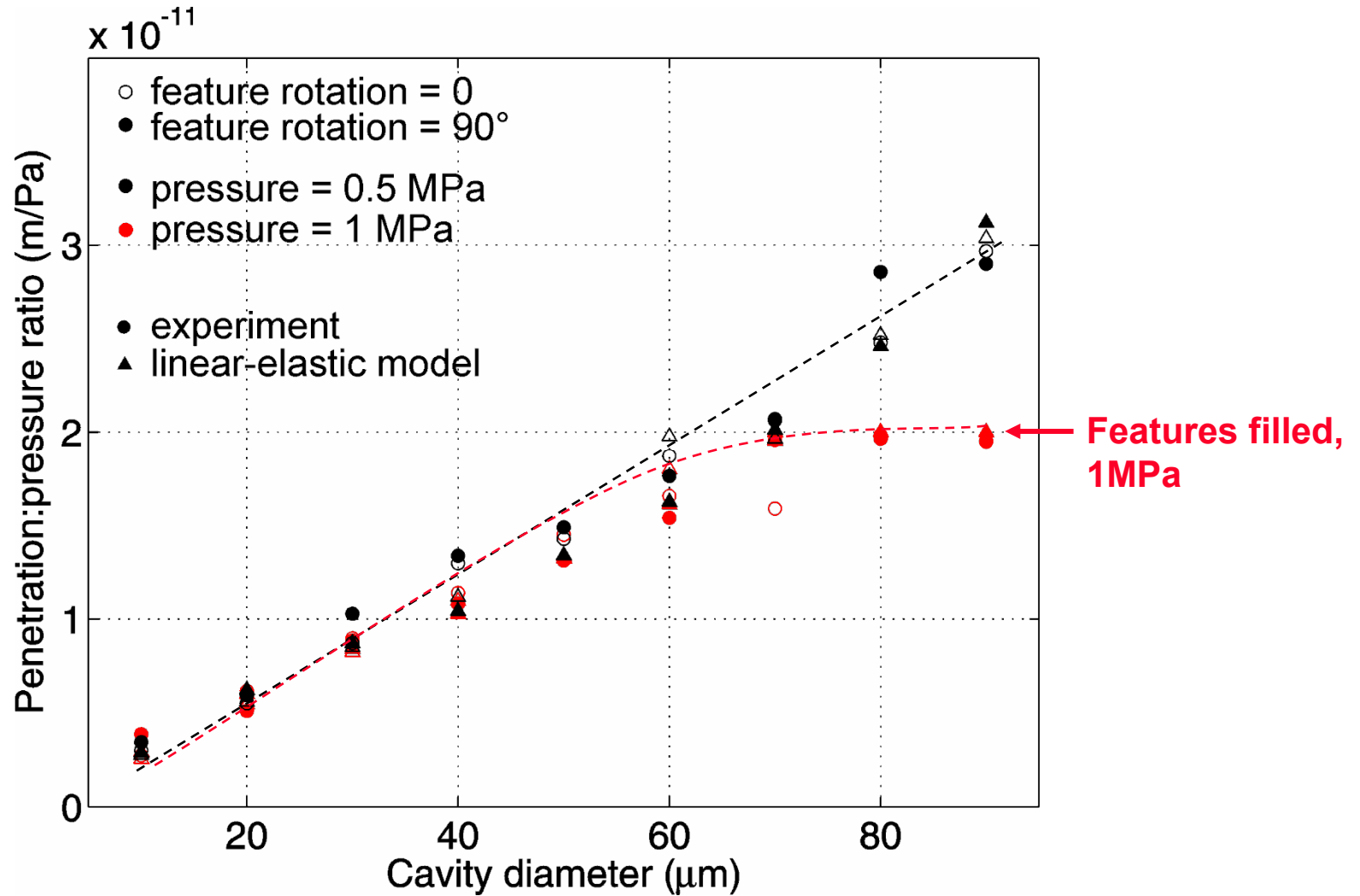


— Thick, linear-elastic material model
— Experimental data

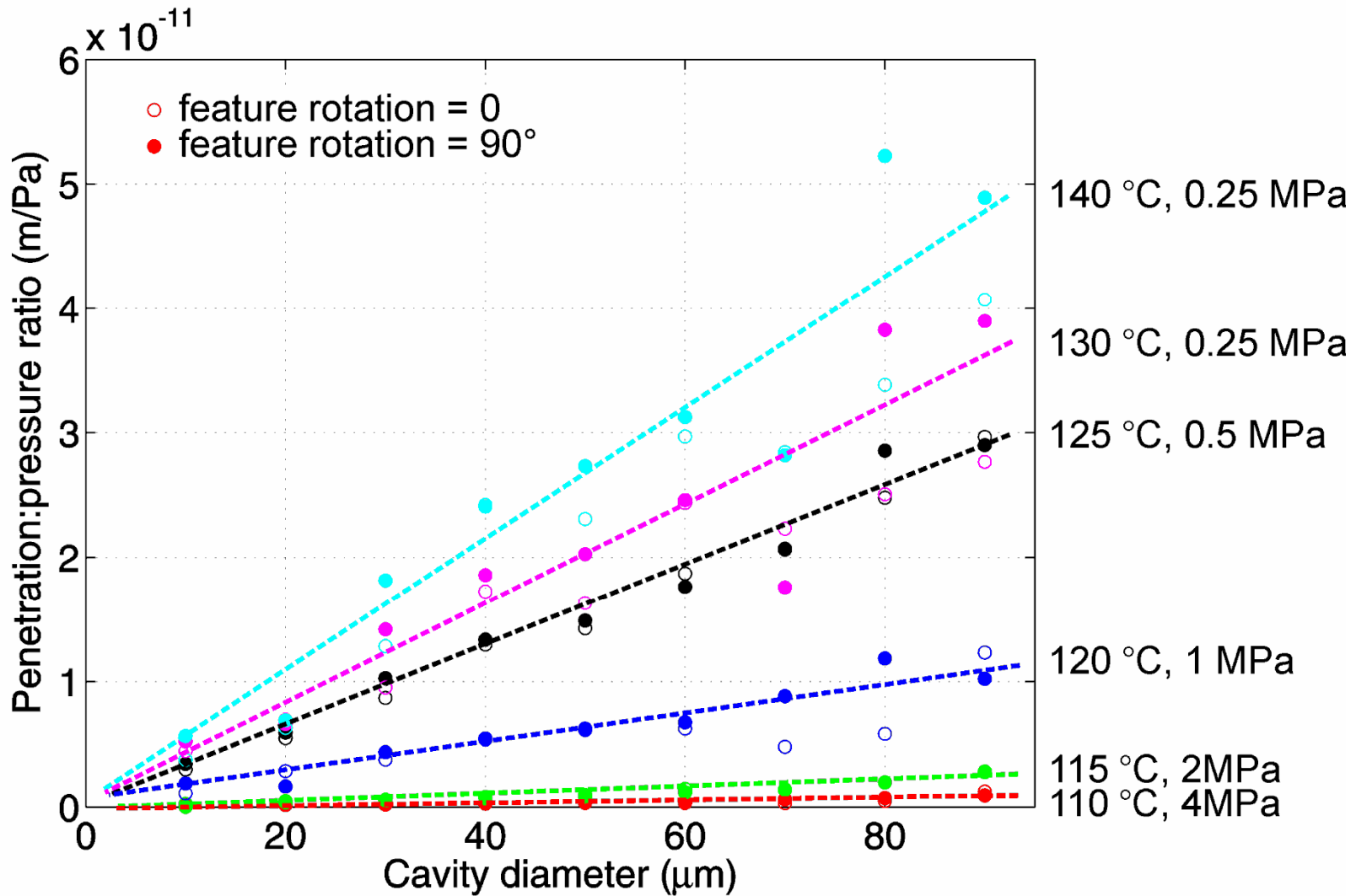
Linear-elastic model succeeds at 125 °C, $p_{ave} = 0.5$ MPa



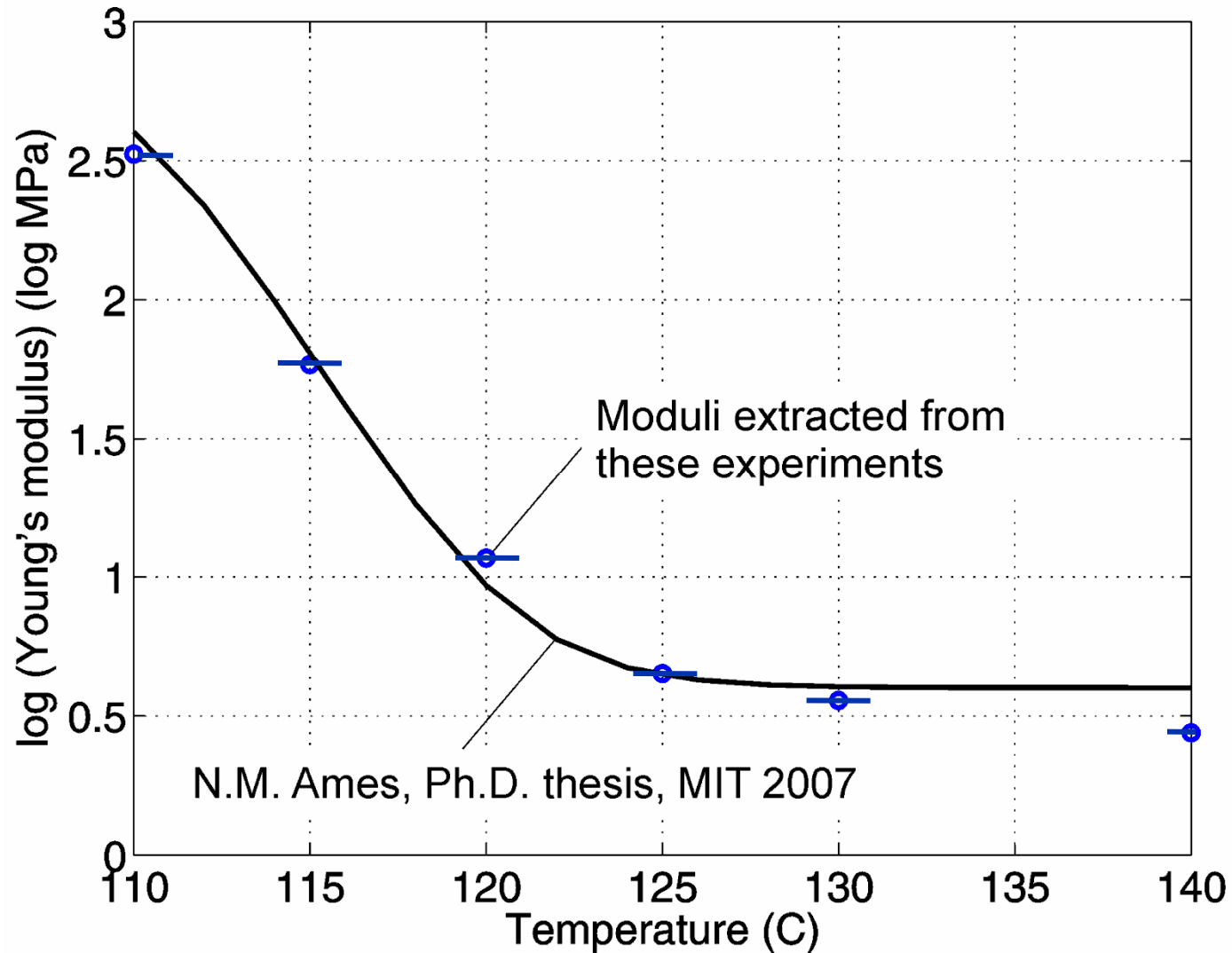
Linear-elastic model succeeds at 125 °C, $p_{ave} = 1$ MPa



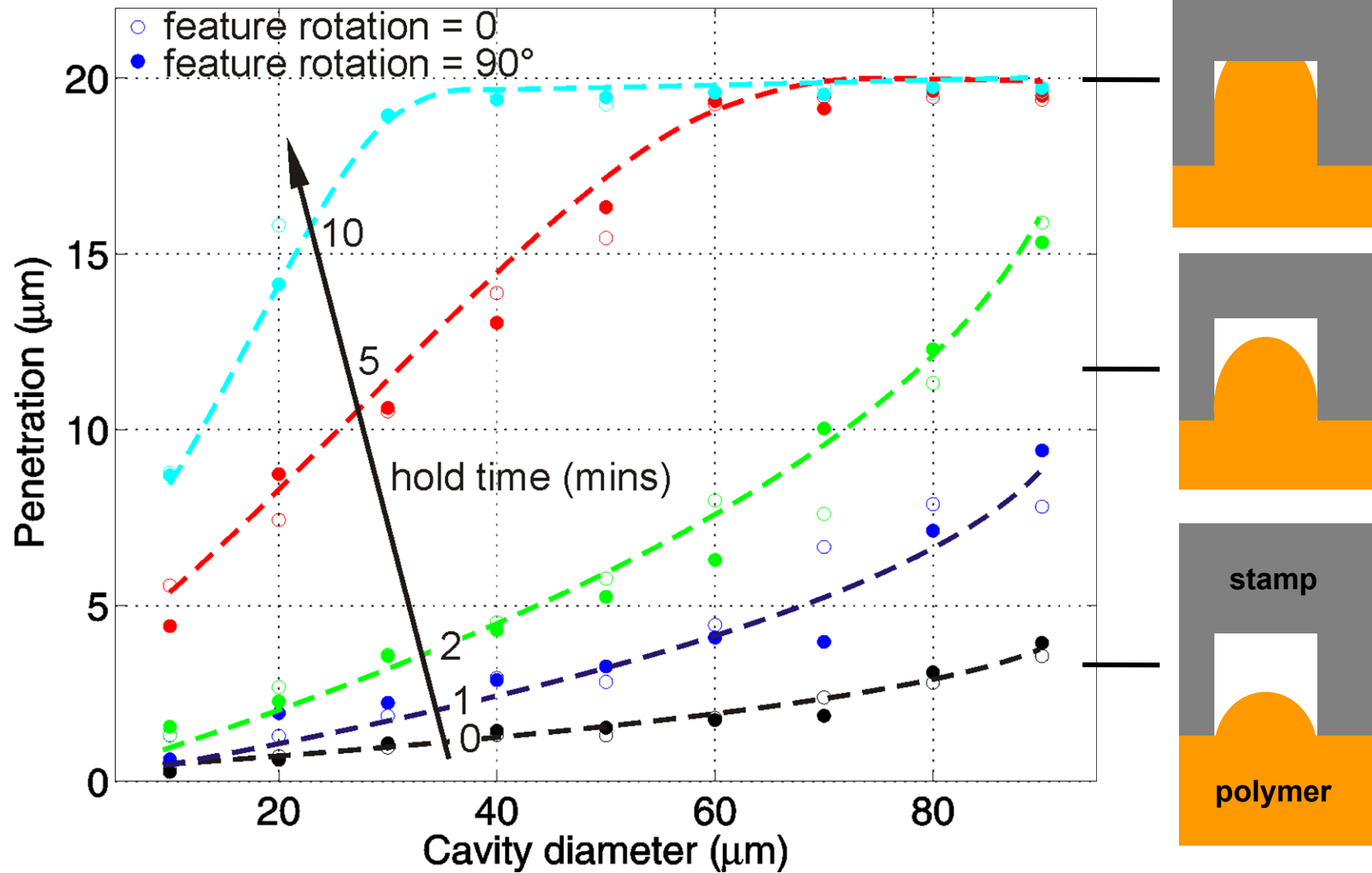
Linear elastic model succeeds below yielding at other temperatures



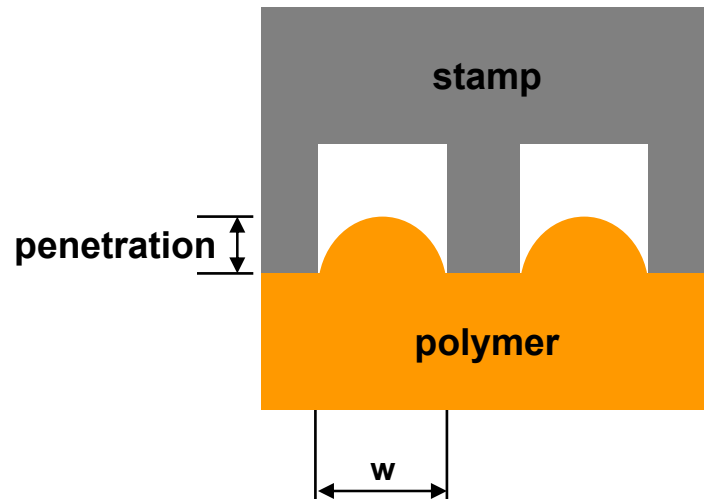
Extracted PMMA Young's moduli from 110 to 140 °C



Material flows under an average pressure of 8 MPa at 110 °C



Yielding at 110 °C

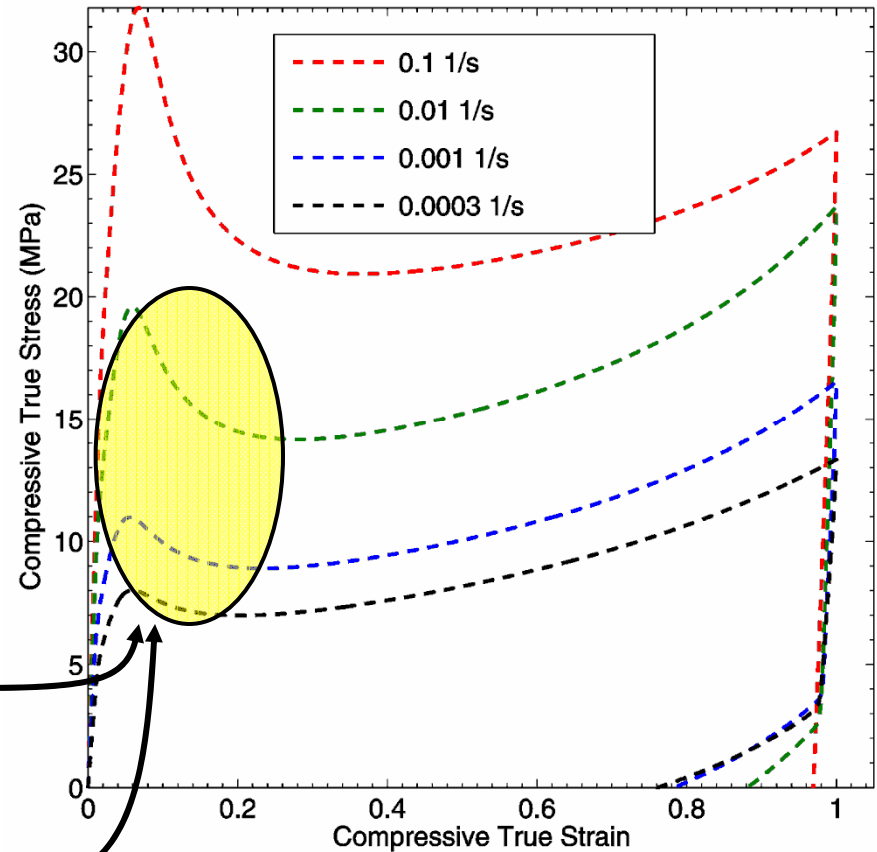
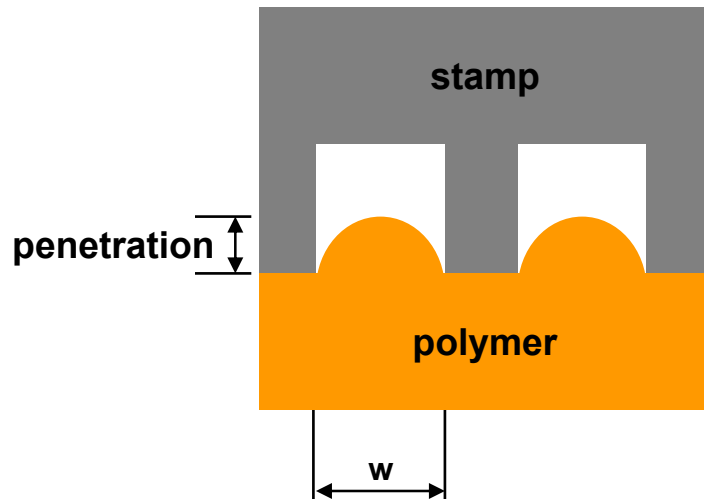


Simple estimates of strain rate:

$$\frac{\text{penetration}}{\frac{w}{2} t_{\text{hold}}} \left\{ \begin{array}{l} 10^{-3} \text{ to } 10^{-1} \text{ during loading} \\ 10^{-4} \text{ to } 10^{-3} \text{ during hold} \end{array} \right.$$

**Local contact pressure
at feature corners > 8 MPa**

Yielding at 110 °C



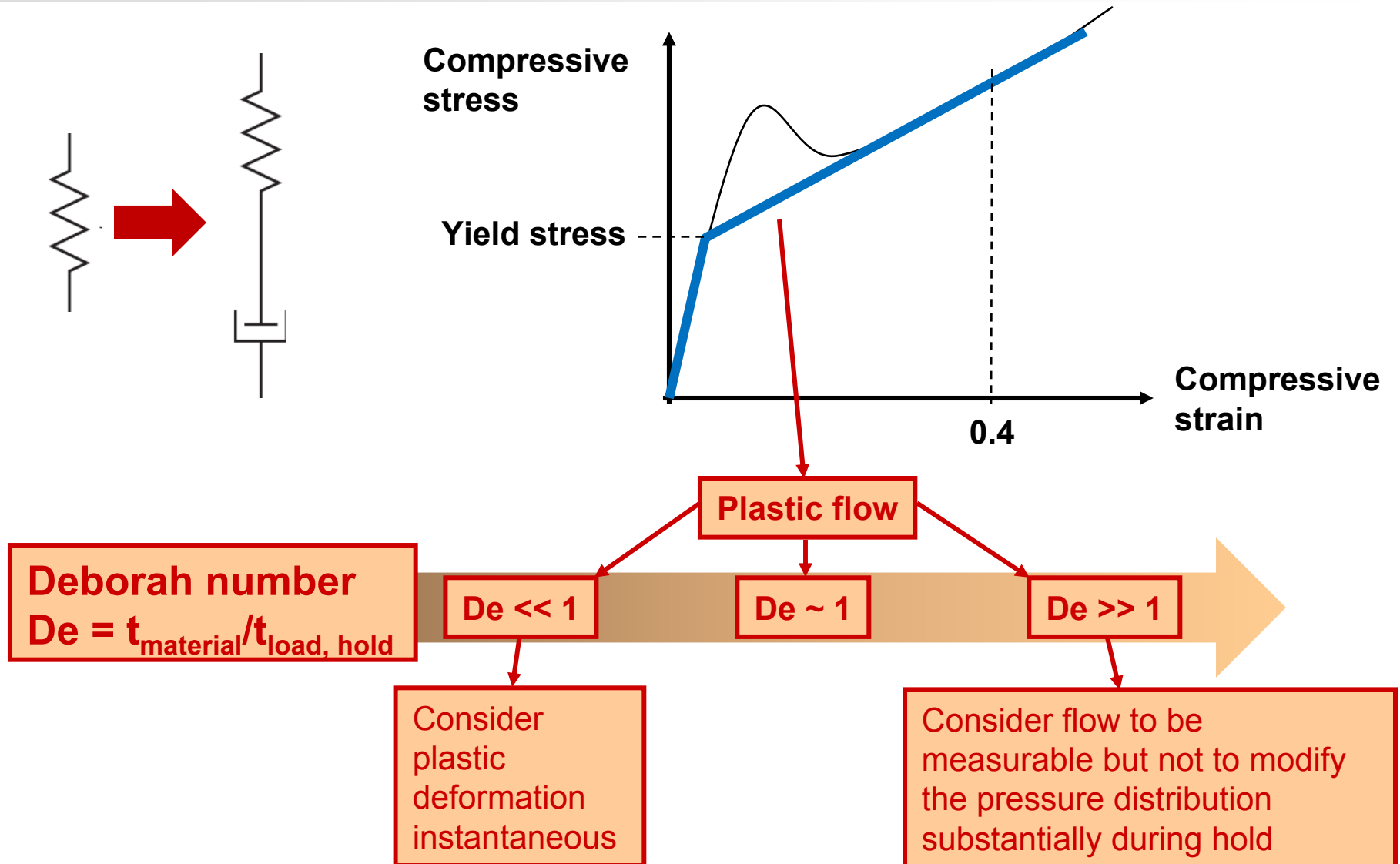
Simple estimates of strain rate:

$$\frac{\text{penetration}}{\frac{w}{2} t_{\text{hold}}} \begin{cases} 10^{-3} \text{ to } 10^{-1} \text{ during loading} \\ 10^{-4} \text{ to } 10^{-3} \text{ during hold} \end{cases}$$

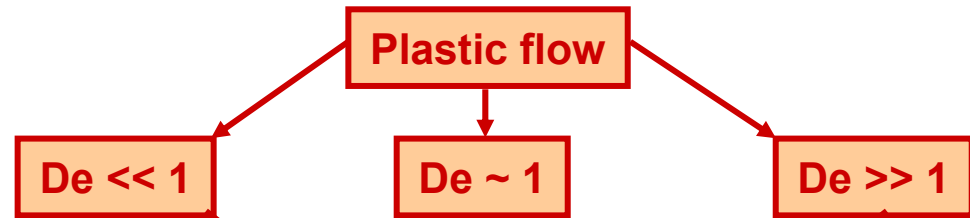
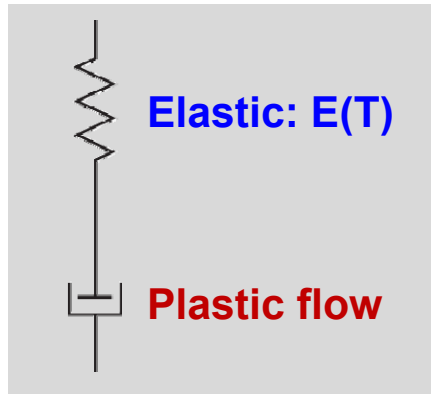
Local contact pressure at feature corners > 8 MPa

N.M. Ames, Ph.D. Thesis, MIT, 2007

Modelling combined elastic/plastic behavior



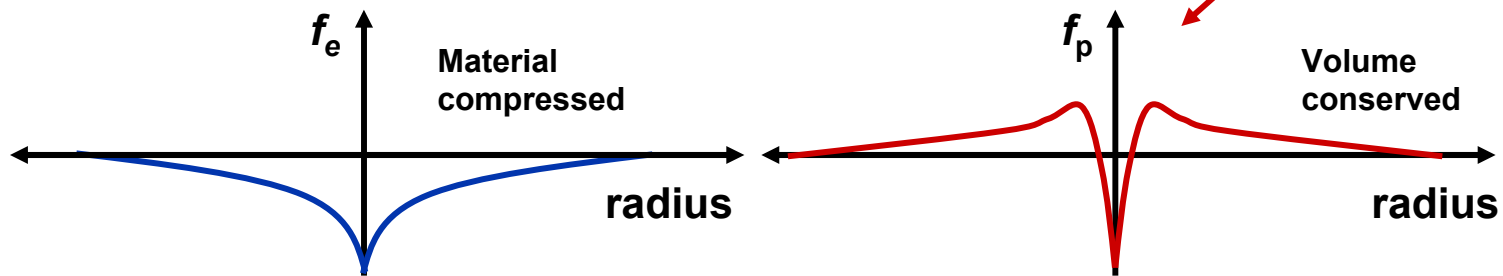
Modelling combined elastic/plastic behavior



$$w(x,y) = p(x,y) * f_e(x,y) + \left[p(x,y) - p_{yield} \right] * \left(A + Bt_{hold} \right) f_p(x,y)$$

Existing linear-elastic component

Tuned to represent cases from capillary filling to non-slip Poiseuille flow



Summary and future directions

- **The merits of a linear-elastic embossing polymer model have been probed**
- **This simulation approach completes an 800x800-element simulation in:**
 - ~ 45 s (without filling)
 - ~ 4 min (with some filling)
- **Our computational approach can be extended to capture yielding and plastic flow**
- **Is a single pressure distribution solution sufficient to model visco-elasto-plastic behaviour?**
- **Abstract further: mesh elements containing many features**

Acknowledgements

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